

Withdrawal/Redaction Sheet

Clinton Library

DOCUMENT NO. AND TYPE	SUBJECT/TITLE	DATE	RESTRICTION
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001. fax	Margaret Kindling/SEMI to Barbara Bernstein/OTSP re meeting (partial) (1 page)	07/09/1993	b(6)
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COLLECTION:

Clinton Presidential Records
Office of Science and Technology Policy
Skip Johns
OA/Box Number: 10672

FOLDER TITLE:

Semiconductor Equipment and Materials International (SEMI)

2008-1524-F
kc1208

RESTRICTION CODES

Presidential Records Act - [44 U.S.C. 2204(a)]

P1 National Security Classified Information [(a)(1) of the PRA]
P2 Relating to the appointment to Federal office [(a)(2) of the PRA]
P3 Release would violate a Federal statute [(a)(3) of the PRA]
P4 Release would disclose trade secrets or confidential commercial or
financial information [(a)(4) of the PRA]
P5 Release would disclose confidential advice between the President
and his advisors, or between such advisors [(a)(5) of the PRA]
P6 Release would constitute a clearly unwarranted invasion of
personal privacy [(a)(6) of the PRA]

C. Closed in accordance with restrictions contained in donor's deed
of gift.

PRM. Personal record misfile defined in accordance with 44 U.S.C.
2201(3).

RR. Document will be reviewed upon request.

Freedom of Information Act - [5 U.S.C. 552(b)]

b(1) National security classified information [(b)(1) of the FOIA]
b(2) Release would disclose internal personnel rules and practices of
an agency [(b)(2) of the FOIA]
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information [(b)(4) of the FOIA]
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personal privacy [(b)(6) of the FOIA]
b(7) Release would disclose information compiled for law enforcement
purposes [(b)(7) of the FOIA]
b(8) Release would disclose information concerning the regulation of
financial institutions [(b)(8) of the FOIA]
b(9) Release would disclose geological or geophysical information
concerning wells [(b)(9) of the FOIA]

FOIA MARKER

This is not a textual record. This is used as an administrative marker by the William J. Clinton Presidential Library Staff.

Collection/Record Group: Clinton Presidential Records
Subgroup/Office of Origin: Office of Science and Technology Policy
Series/Staff Member: Skip Johns
Subseries:

OA/ID Number: 10672
FolderID:

Folder Title:
Semiconductor Equipment and Materials International (SEMI)

Stack:	Row:	Section:	Shelf:	Position:
S	66	4	5	1

Semiconductor Equipment
and Materials International

June 29, 1993

The Honorable Dr. John Gibbons
Assistant to the President
Office of Science and Technology Policy
Old Executive Office Building - Room 360
17th Street and Pennsylvania Ave., N.W.
Washington, D.C. 20500

Dear Dr. Gibbons:

On behalf of Semiconductor Equipment and Materials International (SEMI), I would like to schedule a meeting for William Reed, President of SEMI, on Thursday, July 15th at 9:30 am. SEMI is a trade association which represents over 800 U.S. manufacturers of semiconductor and flat panel display capital equipment and materials. The majority of our members are small, entrepreneurial firms, but collectively they form the foundation for the U.S. electronics infrastructure. Our industry generates over \$9 billion in annual sales and employs approximately 100,000 people in 39 states. SEMI is active on behalf of our members in major markets around the world, including Europe, Korea, Japan and South East Asia. Attached is a copy of our public policy agenda.

We want to discuss federal microelectronics research and development funding for high definition systems and advanced lithography. We would also like to discuss ways SEMI can work more closely with OSTP to increase our industry's understanding of and participation in Presidential initiatives focusing on advanced manufacturing and advanced materials.

Our office will be contacting you to determine whether this date is convenient for you. Thank you for your consideration.

Sincerely,

Victoria Hadfield
Manager, Government Relations

cc: Katherine Gillman
Timothy Newell

Date Rec'd 6/29
ACTION to Gillman
INFO to SB
7/14 Wed.
3:30
SIG of _____
Stationery _____
DATE DUE 7/9



GOVERNMENT RELATIONS

Semiconductor Equipment and Materials International 1993 Public Policy Agenda

Tax/Investment Policy

- Depreciation:** Accelerate depreciation of semiconductor production equipment.
- R&D Tax Credit:** Increase the effectiveness of R&E Credit and make it permanent.
- Investment Tax Credit:** Establish investment tax credit to encourage investment in critical technology sectors.

Technology Policy

- R&D Funding:** Target R&D funding to priority technology areas (e.g. advanced lithography, flat panel displays).
- Intellectual Property:** Promote protection of intellectual property rights of SEMI members in all markets, bilaterally and through the GATT.

Trade Policy

- Market Access:** Promote free trade and open market access worldwide.
- Tariffs:** Promote an end to tariffs on semiconductor production equipment in the GATT Uruguay Round.
- Technology Transfer:** Reform U.S. Government export control policies to meet new world order; Eliminate national security controls on exports of dual-use semiconductor manufacturing equipment (SME) products to former Soviet Bloc countries; Reduce overly broad U.S. non-proliferation controls on SME.

Semiconductor Equipment
and Materials International



FACSIMILE TRANSMISSION COVERSHEET

DATE 6/29 NUMBER OF PAGES (INCLUDING COVER) 3

TO: Sue Dachtel - Dr. Gibbon's Office

COMPANY: OSTP

FAX: _____

FROM: SEMI WASHINGTON OFFICE - TELEPHONE 202/457-9584

SENT BY: Margaret Kindling

SUBJECT: Request for Mtg with Dr. Gibbons

MESSAGE:

IF YOU EXPERIENCE ANY DIFFICULTIES IN RECEIVING THIS FAX,
PLEASE CALL 202/457-9584

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Semiconductor Equipment
and Materials International



*waved
7/9*

[001]

FACSIMILE CORRESPONDENCE

Date: July 9, 1993
To: Barbara Bernstein, OSTP
From: Margaret Kindling, SEMI
Re: Meeting with Dr. Lionel Johns - July 14, 1993

=====

Barbara:

The following people will be attending the meeting next Wednesday, July 14th with Dr. Johns:

William H. Reed, President, SEMI

Birthdate

Victoria Hadfield, Manager/Govt Relations, SEMI

Birthdate

(b)(6)

Seymour Kraut, Bull Computers

Birthdate

Please contact Ms. Hadfield if you have any questions. Thank you for your assistance.

Semiconductor Equipment
and Materials International

June 29, 1993

The Honorable Dr. John Gibbons
Assistant to the President
Office of Science and Technology Policy
Old Executive Office Building - Room 360
17th Street and Pennsylvania Ave., N.W.
Washington, D.C. 20500

Date Rec'd 6/29
ACTION to Gibbons
INFO to SB

SIG of _____
Stationery _____
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*7/6/93
she record
SB
John*

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Our office will be contacting you to determine whether this date is convenient for you. Thank you for your consideration.

Sincerely,

Victoria Hadfield
Manager, Government Relations

cc: Katherine Gillman
Timothy Newell

*Call Christ.
as 7/9 when
Schedule
7/9 - copy of calendar
to Christ, Tim,
Kathy, Mark
7/14 3:30*

457-9584



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Semiconductor Equipment
and Materials International



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SENT BY: Margaret Kindling

SUBJECT: Request for Mtg with Dr. Gibbons

MESSAGE:

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July 26, 1993

Dr. Lionel Johns
Assistant Director
Office of Science & Technology Policy
Old Executive Office Bldg.
17th & Pennsylvania Ave., NW
Washington, DC 20500

Dear Dr. Johns:

Thank you for taking the time to meet with Bill Reed and me on July 14, 1993. We are aware of how demanding your schedule is at the moment and appreciated your attentiveness to our concerns.

In our meeting we mentioned our views regarding the need for Administration support of manufacturing efforts in ARPA's high definition systems program and the potential beneficial impact of this program on upstream suppliers of flat panel display equipment and materials in our industry. Our industry is willing to work with the U.S. Government to address the challenges inhibiting the development of a U.S. infrastructure in flat panel display manufacturing tools and equipment. But without a strong customer base of display manufacturers in the United States, this infrastructure will develop much more rapidly in Japan and only a few U.S. companies will participate.

The issue of lithography which you raised in our meeting is a troubling one. SEMI believes it is important to take steps to ensure the viability of the remaining key segments of the lithography business which the U.S. continues to possess, including maskmaking equipment, mask producers, resist manufacturers, and other suppliers of related gear and materials. As we discussed in our meeting, this can only be done with a full commitment from the semiconductor industry in the U.S., as well as the government.

Thank you once again for meeting with us. Please let us know if we can be of assistance in the future.

Sincerely,

A handwritten signature in cursive script that reads 'Victoria Hadfield'.

Victoria Hadfield
Manager, Government Relations